SEMIPROBE MEMS-0515 Wafer Probe Station Owner's Manual

Specific Requirements

The customer wanted to test 200 mm silicon MEMS wafers using a manual probe system integrated with a Polytec MSA-500 MEMS Motion Analyzer. The motion analyzer would measure a variety of MEMS devices while in-plane and out-of-plane. The wafer chuck would need to be tilted in a variety of directions. The devices would be contacted with a probe card as well as individual manipulators with coaxial probe arms and DCprobe needles.

SemiProbe Solution

- M-8 Manual 200 mm probe system:
    - 200 mm of X, Y, Z and theta stage
    - Rapid Align Stage provides both coarse and fine stage movement
    - Vibration isolation table
- Integrated with a Polytec MSA-500 motion analyzer
- 200 mm wafer chuck (non-thermal) with X and Y in-plane and out-of-plane adjustability for the MSA-500
- Compound microscope:
    - movement of 50 mm of X and Y
    - pneumatic microscope lift (MSA 500)
- Six manual three-axis manipulators with coaxial probe arms, cables and DC probes
- Probe card holder

Customer Support

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